

# Room Temperature Broadband Bi<sub>2</sub>Te<sub>3</sub>/PbS Colloidal Quantum Dots Infrared Photodetectors

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## S1. Discussion on magnetron sputtering process of Bi<sub>2</sub>Te<sub>3</sub> film

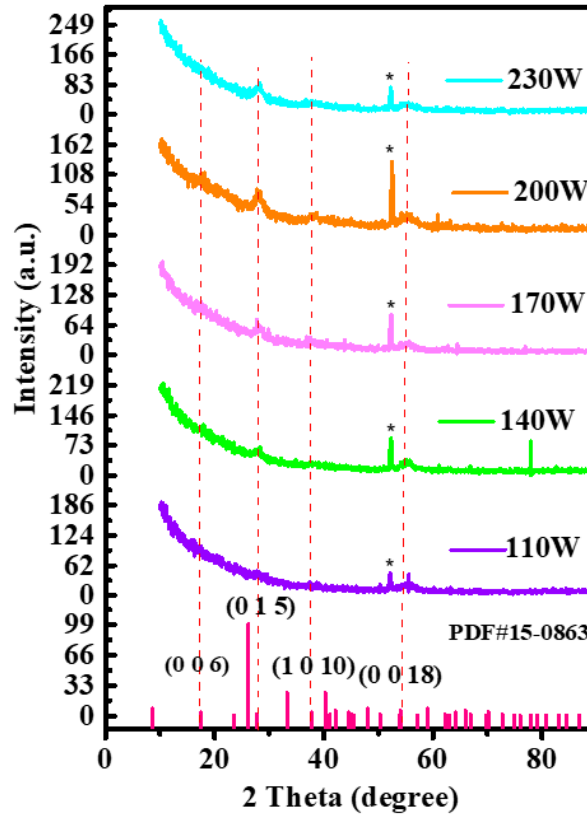
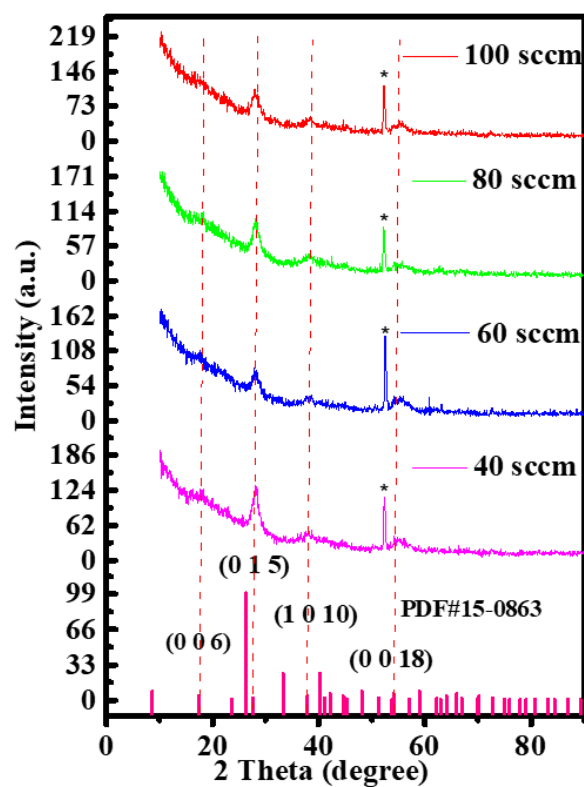
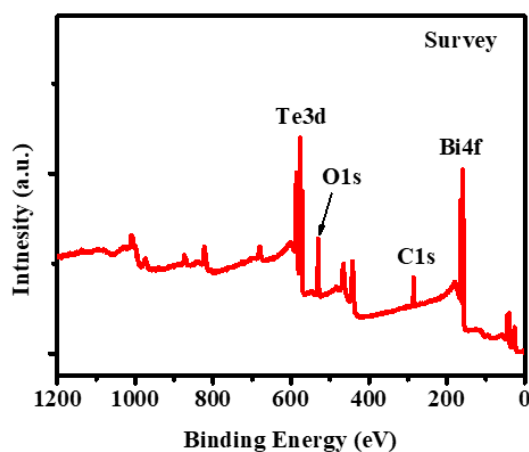


Figure S1. X-ray diffraction (XRD) patterns of Bi<sub>2</sub>Te<sub>3</sub> film grown under different sputtering power

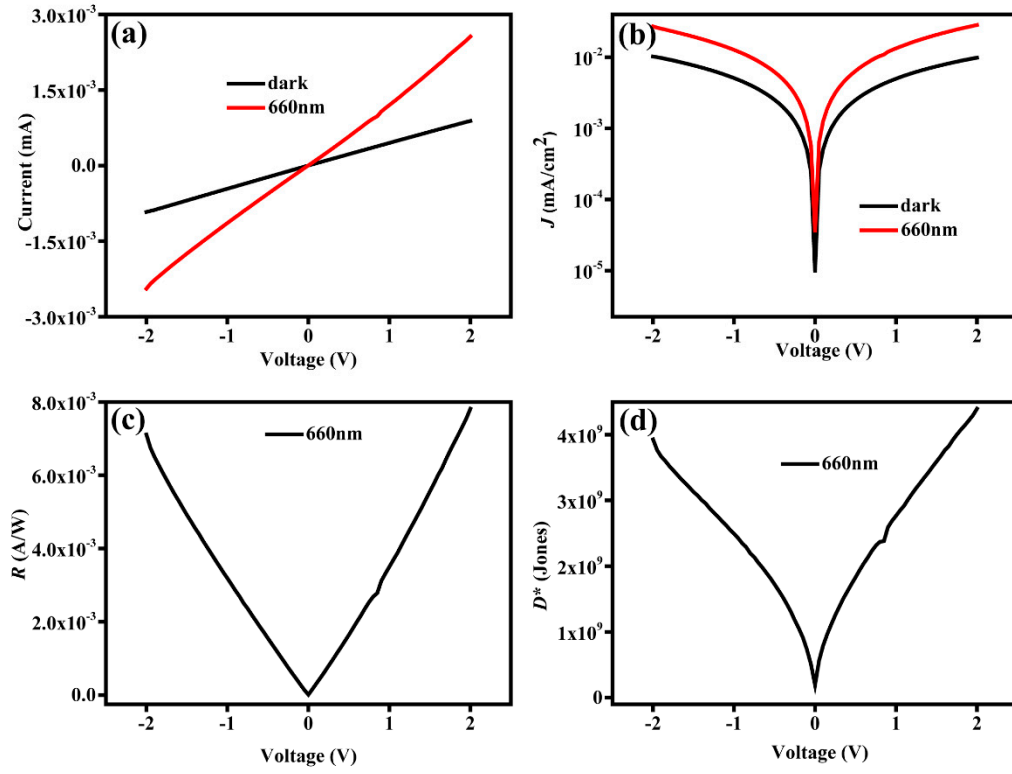


**Figure S2.** X-ray diffraction (XRD) patterns of Bi<sub>2</sub>Te<sub>3</sub> film grown under different gas rate



**Figure S3.** X-ray photoelectron spectroscopy (XPS) survey scan of Bi<sub>2</sub>Te<sub>3</sub> film

## S2. Discussion on PbS devices (without Bi<sub>2</sub>Te<sub>3</sub>)



**Figure S4.** PbS devices without Bi<sub>2</sub>Te<sub>3</sub>. (a, b) *I-V* curves of the photodetector under 660 nm illumination. (c) Plot of responsivity ( $R$ ) against voltage ( $V$ ). (d) Plot of detectivity ( $D^*$ ) against voltage ( $V$ ).